

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 244702US2			SERIAL NO. New Application	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Takeshi YOSHIDA, et al.				
				FILING DATE Herewith			GROUP	
U.S. PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
	AA							
	AB							
	AC							
	AD							
	AE							
	AF							
	AG							
	AH							
	AI							
	AJ							
	AK							
	AL							
	AM							
	AN							
FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO			
24	AO	2002-189000	07/05/02	Japan		X		
	AP							
	AQ							
	AR							
	AS							
	AT							
	AU							
	AV							
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)								
24	AW	Stephen B. IPPOLITO, et al., "HIGH-RESOLUTION IC INSPECTION TECHNIQUE", Department of Electrical and Computer Engineering and the Photonics Center, Boston University, (12 pages)						
24	AX	Stephen B. IPPOLITO, et al., "COMPARISON OF NUMERICAL APERTURE INCREASING LENS AND STANDARD SUBSURFACE MICROSCOPY", Depts. of Physics and Electrical and Computer Engineering and the Photonics Center, Boston University, (2 pages)						
24	AY	Stephen B. IPPOLITO, et al., "HIGH RESOLUTION SUBSURFACE MICROSCOPY TECHNIQUE", Boston University Photonics Center, Depts. of Physics and Electrical and Computer Engineering, (2 pages)						
	AZ						<input type="checkbox"/> Additional References sheet(s) attached	
Examiner <i>K. P. ...</i>					Date Considered <i>3/16/15</i>			
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								